

Cautions in Using the DFM2800

Introduction

This technical newsletter notifies you of the points to keep in mind when performing automatic operation of the DFM2800.

Applicable model

DFM2800

Points to keep in mind

When the wafer transfer arm loads/unloads a wafer to/from the inspection table or attachment table, the both units may vacuum each other, which may lead to breakage of the wafer transfer arm, depending on the parameter settings of the DFM2800, individual difference among machines, or workpiece conditions.

If setting “Wafer transfer arm: Vacuum break time (the factory default: 0.3 sec)” (parameter 365) and “Wafer inspection table: Vacuum break time (the factory default: 0.3 sec)” (parameter: 432) at too small values and performing an unload operation, the wafer transfer arm tries to move up even when the vacuum breakage has not been completed (there is still vacuum pressure). This is the cause of the problem described above.

The problem may occur even with the factory default setting. Therefore, please change the parameter settings as follows:

- Parameter 365: “Wafer transfer arm: Vacuum break time”

Factory default: 0.3 sec ⇒ Change it to 3.0 sec.

- Parameter 432: “Wafer inspection table: Vacuum break time”

Factory default: 0.3 sec ⇒ Change it to 3.0 sec.

Technical Newsletter

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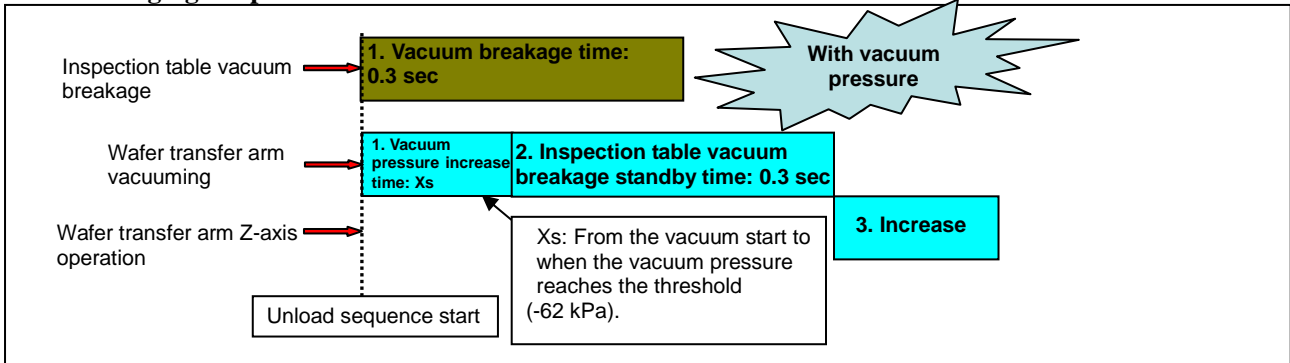
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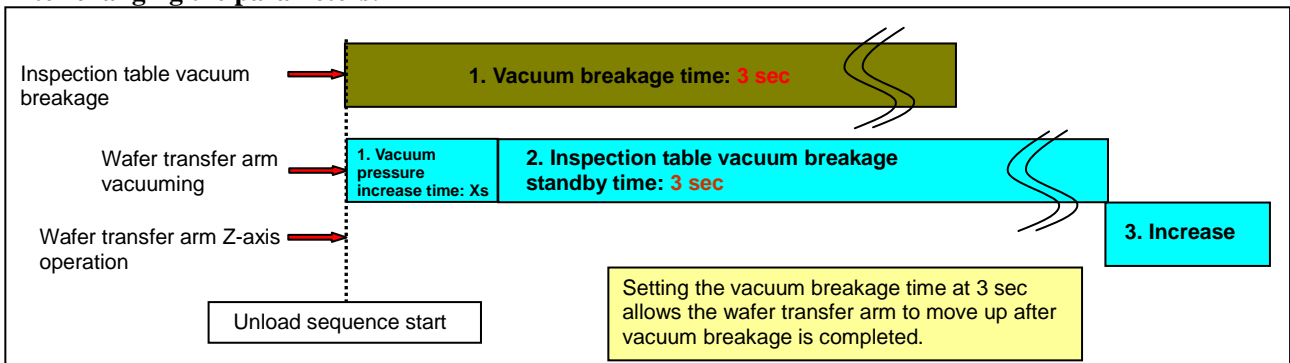
Explanation of the operation sequences

Example of “inspection table vacuum breakage” ⇒ “wafer transfer arm vacuuming”:

Before changing the parameters:



After changing the parameters:



Inquiry

If you have any questions regarding this matter, please contact your DISCO sales representative or nearest DISCO service office